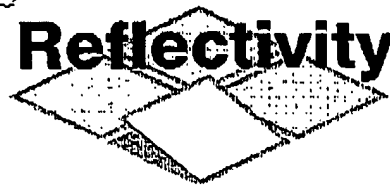


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We are in receipt of the Notice of Allowance and in reviewing the file we noticed that we have not received back the Information Disclosure Statement PTO 1449 forms that we filed on October 7, 2004. Attached please find the forms. Please sign and send back to us.

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	09/854,884
		Filing Date	8/17/01
		First Named Inventor	Patel
		Art Unit	1783
		Examiner Name	Olsen, Allan
Sheet 1 of 5	Attorney Docket Number	P68-US	

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number Number - Kind Code ¹ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		US- 3,511,727	05-12-1970	Hays, R.G.	
		US- 4,190,488	02-28-1980	Winters, H.F.	
		US- 4,310,380	12-12-1982	Flamm et al.	
		US- 4,499,953	02-12-1985	Cook et al.	
		US- 6,051,503	04-18-2000	Bhardwal, J.K.	
		US- 6,438,229	08-20-2002	Tal et al.	
		US- 6,182,387	12-19-2000	Tal et al.	
		US- 6,290,884 B1	09-18-2001	Patel et al.	
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		US- 2001/0002663 A1	06-07-2001	Tal et al.	
		US- 5,439,553	08-09-1995	Grant et al.	
		US- 2002/0033229 A1	03-21-2002	Leboutz et al.	
		US- 2002/0198524 A1	12-28-2002	Hubers, et al.	
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		US- 2002/0185698	12-12-2002	Reid	
		US- 2002/0121502 A1	09-15-2002	Patel, et al.	
		US- 5,835,256	11-10-1998	Hubers, A.	
		US- 2002/0047172 A1	04-25-2002	Reid	
		US- 2003/0186342 A1	09/04/03	Chinn, et al.	

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Examiner Initials	Cite No.	Foreign Patent Document Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		EP-0704884-A2	04-03-1998	Mehta, J.	
		EP-0822582-A2	02-04-1998	Bhardwal, J.K.	
		EP-0822584-A2	04-04-1998	Bhardwal, J.K.	
		WO-99/49506	09-30-1999	McQuarrie, A.D.	
		EP-0878824-A2	11-18-1998	McQuarrie et al.	
		EP-0878824-A3	01-19-2000	McQuarrie et al.	
		JP-1982/57098679-A	08-18-1982	Tsunetoshi, A.	
		JP-1983/58130529-A	08-04-1983	Yoshihiro et al.	
		JP-1985/60057938-A	04-03-1985	Katsumi et al.	
		WO-88/32183	07-23-1988	Tal et al.	

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			Filing Date	9/17/01	
			First Named Inventor	Patel	
			Art Unit	1763	
			Examiner Name	Olsen, Allan	
Sheet	2	of	6	Attorney Docket Number	P88-US

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No. 1	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code 2 (if known)			
		US- 6,409,876 B1	06-25-2002	McQuarrie, et al.	
		US- 6,396,618 B1	05-28-2002	Huibers, et al.	
		US- 6,576,489 B2	06/10/03	Leung, et al.	
		US- 6,238,581	05-29-2001	Hawkins, et al.	
		US- 6,115,172	09-05-2000	Joong	
		US- 6,204,080	03-20-2001	Hwang	
		US- 2003/0071015 A1	04/17/03	Chinn, et al.	
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		US- 6,197,610 B1	03/06/2001	Toda	
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		US- 2003/0124848 A1	07/03/03	Chinn, et al.	
		US- 2003/0218986 A1	11/27/03	Rattner, et al.	
		US- 4,551,197	11/05/85	Gillette, et al.	
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FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No. 1	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code 3	Number 4 - Kind Code 5 (if known)			
			JP-1997/09251881-A	09-22-1997	Kazuaki et al.	
			JP-1999/10313128-A	11-24-1998	Hanmin et al.	
			JP-1998/10317169-A	12-02-1998	McQuarrie et al.	
			JP-1998/61187238-A	08-20-1998	Nobuo et al.	
			JP-1998/61270830-A	12-01-1998	Toru, T.	
			JP-1987/62071217-A	04-01-1987	Toru et al.	
			JP-1988/63155713-A	08-28-1988	Tadashi, F.	
			JP-1988/61053732-A	03-17-1988	Arata et al.	
			JP-1988/61134018-A	06-21-1988	Shinji et al.	
			JP-1988/61181131-A	08-13-1988	Shinji et al.	

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Application Number				09/954,864	
Filing Date				9/17/01	
First Named Inventor				Patel	
Art Unit				1763	
Examiner Name				Olsen, Allan	
Attorney Docket Number				P68-US	
Sheet	3	of	6		

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FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No.†	Foreign Patent Document‡		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Paragraph or Relevant Figures Appear	T
		Country Code§ - Number¶ - Kind Code* (if known)					
		JP-1989/01208834-A		08-22-1989	Nobuo et al.		
		JP-1989/10217921-A		08-31-1989	Tsumoo et al.		
		JP-1990/02250323-A		10-08-1990	Susumu et al.		
		JP-1991/03012921-A		01-21-1991	Nobuo et al.		
		JP-1992/04096222-A		03-27-1992	Atsuyuki, A.		
		JP-1995/07029823-A		01-31-1995	Hiroshi, T.		

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		Filing Date	9/17/01		
		First Named Inventor	Patel		
		Group Art Unit	1783		
		Examiner Name	Olsen, Allan		
Sheet	4	of	6	Attorney Docket Number	P88-US

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume/issue number(s), publisher, city and/or country, where published	T ²
		ALIEV et al., "Development of Si(100) Surface Roughness at the Initial Stage of Etching in F2 and XeF2 Gases Ellipsometric Study", Surface Science 442 (1999), pp. 208-214.	
		GLIDEMEISTER, J.M., "Xenon Difluoride Etching System" (Nov. 17, 1997).	
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		STRELLER et al., "Selectivity in Dry Etching of Si (100) and XeF2 and VUV Light", Elsevier Science B.V., Applied Surface Science Vol. 106 (1996), pp. 341-348.	
		VUGTS et al., "Si/XeF2 Etching: Temperature Dependence", J. Vac. Sci. Technol. A 14(5) (Sep/Oct 1996), pp. 2768-2774.	
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		Kurt Williams, Etch Rates for Micromachining Processing-Part II, 2003 IEEE. Pgs 761-778, Journal of Microelectromechanical Systems, Vol. 12, No. 8, December 2003.	
		WINTERS et al., "The Etching of Silicon with XeF ₂ Vapor", Appl. Phys. Lett., Vol. 34(1) (January 1, 1979), pp. 70-73.	
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		CHAN et al., "Gas Phase Pulse Etching of Silicon for MEMS with Xenon Difluoride", Engineering Solutions for the Next Millennium: 1999 IEEE Canadian Conference on Electrical and Computer Engineering, Edmonton, Alberta, Vol. 3 (May 9 - 12, 1999), pp. 1637-1642 (abstract only).	
		CHANG et al., "Gas-Phase Silicon Micromachining with Silicon Difluoride", Proceedings of the SPIE - The International Society for Optical Engineering, Vol. 2641 (1995), pp. 117-128 (abstract only).	

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		Filing Date	9/17/01
		First Named Inventor	Patel
		Group Art Unit	1763
		Examiner Name	Olsen, Allan
		Attorney Docket Number	P68-US
Sheet	6	of	6

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